

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In re Application of:**

Steven J. Simmons

**Serial No.:** Not yet assigned

**Filed:** August 29, 2003

**For:** YIELD BASED, IN-LINE DEFECT  
SAMPLING METHOD

**Examiner:** Unknown

**Group Art Unit:** Unknown

**Attorney Docket No.:** 2269-3640.2US  
(97-1175.02/US)

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**INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

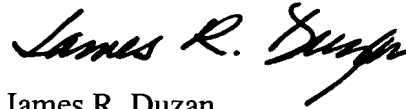
Sir:

The present application is a continuation of application Serial No. 09/847,708, filed May 2, 2001, pending, which is a continuation of application Serial No. 09/138,295, filed August 21, 1998, now U.S. Patent 6,265,232, issued July 24, 2001.

Pursuant to M.P.E.P. 2001.06(b), the Examiner is respectfully requested to consider the information of record in the prior applications, and to confirm in the first Office Action on the merits that such art has in fact been reviewed. A PTO-1449 or PTO/SB/08 form listing all of the information of record in the prior applications is enclosed herewith.

This Information Disclosure Statement is filed within three (3) months of the filing date of the above-identified application, and no certification pursuant to 37 C.F.R. § 1.97(c) or a fee pursuant to 37 C.F.R. 1.17(p) is required.

Respectfully submitted,



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JRD/sls:djp

Enclosures: Form PTO-1449 or PTO/SB/08  
Document in ProLaw

Form PTO-1449

# INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(Use several sheets if necessary)

Docket Number (Optional)

3640.2US (97-1175.02/US)

Application Number

Not yet assigned

Applicant **Steven J. Simmons**Filing Date **August 29, 2003**Group Art Unit **Unknown**

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	4,376,583	03/1983	Alford et al.			
	5,103,166	04/1992	Jeon et al.			
	5,127,726	07/1992	Moran			
	5,240,866	08/1993	Friedman et al.			
	5,294,812	03/1994	Hashimoto et al.			
	5,301,143	04/1994	Ohri et al.			
	5,539,752	07/1996	Berezin et al.			
	5,544,256	08/1996	Brecher et al.			
	5,777,901	07/1998	Berezin et al.			
	6,265,232	07/2001	Simmons			
	6,479,305	11/2002	Kono et al.			
	6,485,991	11/2002	Jitramas et al.			
	6,492,189	12/2002	Yamaguchi			
	6,613,590	09/2003	Simmons			

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

## OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

		S.L. Riley, "Optical Inspection of Wafers Using Large-Area Defect Detection and Sampling", The IEEE International Workshop on Defect and Fault Tolerance in VLSI Systems, November 4-6 1992, pps. 12-21.
		KLA 255X Software V3.6 Option Release Notes, "Automatic Clustering and Sampling of Defects", 19 pages.

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance. Include copy of this form with next communication to the applicant.